


EE C247B - ME C218
Introduction to MEMS Design
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Lecture Module 9: Energy Methods

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Lecture Outline

- Reading: Senturia, Chpt. 10
- Lecture Topics:
 - ↳ Energy Methods
 - ↳ Virtual Work
 - ↳ Energy Formulations
 - ↳ Tapered Beam Example

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Energy Methods

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More General Geometries

- Euler-Bernoulli beam theory works well for simple geometries
- But how can we handle more complicated ones?
- Example: tapered cantilever beam
- Objective: Find an expression for displacement as a function of location x under a point load F applied at the tip of the free end of a cantilever with tapered width $W(x)$

Top view of cantilever's $W(x)$

$W(x) = W \left(1 - \frac{x}{2L_c}\right)$

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Solution: Use Principle of Virtual Work

- In an energy-conserving system (i.e., elastic materials), the energy stored in a body due to the quasi-static (i.e., slow) action of surface and body forces is equal to the work done by these forces ...
- Implication:** if we can formulate **stored energy** as a function of the deformation of a mechanical object, then we can determine how an object responds to a force by determining the shape the object must take in order to **minimize** the **difference U** between the stored energy and the work done by the forces:

$$U = \text{Stored Energy} - \text{Work Done}$$

- Key idea:** we don't have to reach $U = 0$ to produce a very useful, approximate *analytical* result for load-deflection

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More Visual Description ...

Same problem as before: Take a beam & apply a force:

① Apply force.
 ② Beam responds by bending.
 ③ This force has done work: $W = F \cdot y(L_c)$
 ④ Strain generated \rightarrow This means the beam has received an influx of stored energy
 ⑤ Then:
 $U = \text{Stored Energy} - \text{Work Done} \rightarrow 0$
 When we choose the right shape! (This is how we get the beam's response to F!)

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Fundamentals: Energy Density

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- Strain energy density: [J/m³] $w(Q) = \int_0^Q \frac{Q}{C} dQ \rightarrow$ charging a capacitor from 0 \rightarrow Q takes this much work stored energy on a capacitor
- To find work done in straining material

This is a definition, so really can just say it's a definition.

$$w = \int_0^{\epsilon_x} \sigma_x d\epsilon_x \quad \text{x-axis normal stress term}$$

$\sigma_x(\epsilon_x) \rightarrow$ relates stress to strain @ position (x, y, z)

$$[\sigma_x = E\epsilon_x] \Rightarrow w = \int_0^{\epsilon_x} E\epsilon_x d\epsilon_x = \frac{1}{2} E\epsilon_x^2$$

$w(q) = \int_0^q e(q) dq$ $q =$ displacement $e =$ effort } Generic Definition of Work

- Total strain energy [J]:
- Integrate over all strains (normal and shear)

$$W = \iiint \left(\frac{1}{2} E(\epsilon_x^2 + \epsilon_y^2 + \epsilon_z^2) + \frac{1}{2} G(\gamma_{xy}^2 + \gamma_{yz}^2 + \gamma_{zx}^2) \right) dV$$

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Bending Energy Density

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Neutral Axis

$y(x) =$ transverse displacement of neutral axis

- First, find the bending energy dW_{bend} in an infinitesimal length dx : $W =$ width

$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \epsilon_x^2(y') dy'$$

$$\left[\frac{1}{R} = \frac{d^2 y}{dx^2}, \epsilon_x = \frac{y'}{R} \right] \Rightarrow \epsilon_x(y') = y' \frac{d^2 y}{dx^2}$$

$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \left[y' \frac{d^2 y}{dx^2} \right]^2 dy' = \frac{1}{2} E \left(\frac{Wh^3}{12} \right) \left(\frac{d^2 y}{dx^2} \right)^2 dx$$

$$\therefore W_{\text{bend}} = \frac{1}{2} E I_z \int_0^L \left(\frac{d^2 y}{dx^2} \right)^2 dx$$

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Energy Due to Axial Load

• Strain due to axial load S contributes an energy dW_{stretch} in length dx , since lengthening of the different element dx (to ds) results in a strain ϵ_x

$ds = [(dx)^2 + (dy)^2]^{1/2} = dx \left[1 + \left(\frac{dy}{dx} \right)^2 \right]^{1/2} \xrightarrow{\text{Binomial Theorem}} dx \left[1 + \frac{1}{2} \left(\frac{dy}{dx} \right)^2 \right]$
 $\therefore \epsilon_x = \frac{ds - dx}{dx} = \frac{1}{2} \left(\frac{dy}{dx} \right)^2$
 $\left[dW_{\text{axial}} = S \epsilon_x dx = \frac{1}{2} S \left(\frac{dy}{dx} \right)^2 dx \right] \Rightarrow \boxed{W_{\text{axial}} = \frac{1}{2} S \int_0^L \left(\frac{dy}{dx} \right)^2 dx}$

← Axial Strain Energy

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Shear Strain Energy

$$W_{\text{shear}} = \frac{3(EI_z)^2}{4GWh} \int_0^L \left(\frac{d^3 y}{dx^3} \right)^2 dx$$

↑ Shear Modulus

• See W.C. Albert, "Vibrating Quartz Crystal Beam Accelerometer," Proc. ISA Int. Instrumentation Symp., May 1982, pp. 33-44

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Applying the Principle of Virtual Work

- **Basic Procedure:**
 - ↪ Guess the form of the beam deflection under the applied loads
 - ↪ Vary the parameters in the beam deflection function in order to minimize:

$$U = \sum_j W_j - \sum_i F_i u_i$$

Sum strain energies (bracketed over the first sum)
 Assumes point load (arrow pointing to F_i)
 Displacement at point load (arrow pointing to u_i)

- ↪ Find minima by simply setting derivatives to zero
- See Senturia, pg. 244, for a general expression with distributed surface loads and body forces

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Example: Tapered Cantilever Beam

- **Objective:** Find an expression for displacement as a function of location x under a point load F applied at the tip of the free end of a cantilever with tapered width $W(x)$

Top view of cantilever's $W(x)$

$W(x) = W(1 - \frac{x}{2L_c})$

50% taper

$x = L_0$

Adjustable parameters: minimize U

$y(x) = c_2 x^2 + c_3 x^3$

- Start by guessing the solution
 - ↪ It should satisfy the boundary conditions
 - ↪ The strain energy integrals shouldn't be too tedious
 - This might not matter much these days, though, since one could just use matlab or mathematica

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Strain Energy And Work By F

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$$U = \mathcal{W}_{bend} - F \cdot y(L_c)$$

$$\mathcal{W}_{bend} = \frac{1}{2} E \int_0^{L_c} I_z(x) \left(\frac{d^2 y}{dx^2} \right)^2 dx \quad (\text{Bending Energy})$$

$$I_z(x) = \frac{W(x)h^3}{12}$$

$$W(x) = W \left(1 - \frac{x}{2L_c} \right)$$

$$\frac{d^2 y}{dx^2} = 2c_2 + 6c_3 x \quad (\text{Using our guess})$$

Tip Deflection

$$= \frac{1}{24} E W h^3 \int_0^{L_c} \left(1 - \frac{x}{2L_c} \right) (2c_2 + 6c_3 x)^2 dx - F(c_2 L_c^2 + c_3 L_c^3)$$

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Find c_2 and c_3 That Minimize U

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- Minimize $U \rightarrow$ basically, find the c_2 and c_3 that brings U closest to zero (which is what it would be if we had guessed correctly)
- The c_2 and c_3 that minimize U are the ones for which the partial derivatives of U with respect to them are zero:

$$\frac{\partial U}{\partial c_2} = 0 \qquad \frac{\partial U}{\partial c_3} = 0$$

- Proceed:
 - First, evaluate the integral to get an expression for U :

$$U = E W h^3 \left\{ \frac{5c_3^2}{16} L_c^3 + \frac{c_2 c_3}{3} L_c^2 + \frac{c_2^2}{8} L_c \right\} - F(c_2 L_c^2 + c_3 L_c^3)$$

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Minimize U (cont)

- Evaluate the derivatives and set to zero:


$$\frac{\partial U}{\partial c_2} = 0 = \left(\frac{EWh^3}{3} c_3 - F \right) L_c^2 + \left(\frac{EWh^3}{4} c_2 \right) L_c$$

$$\frac{\partial U}{\partial c_3} = 0 = \left(\frac{5}{8} EWh^3 c_3 - F \right) L_c^3 + \left(\frac{EWh^3}{3} c_2 \right) L_c^2$$

- Solve the simultaneous equations to get c_2 and c_3 :

$$c_2 = \left(\frac{84}{13} \right) \frac{FL_c}{EWh^3} \quad c_3 = - \left(\frac{24}{13} \right) \frac{F}{EWh^3}$$

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The Virtual Work-Derived Solution

- And the solution:

$$y(x) = \left(\frac{24F}{13EWh^3} \right) \left(\left(\frac{7}{2} \right) L_c - x \right) x^2$$

- Solve for tip deflection and obtain the spring constant:

$$y(L_c) = \left(\frac{24F}{13EWh^3} \right) \left(\frac{5}{2} \right) L_c^3 \quad k_c = F / y(L_c) = \left(\frac{13EWh^3}{60L_c^3} \right)$$

- Compare with previous solution for constant-width cantilever beam (using Euler theory):

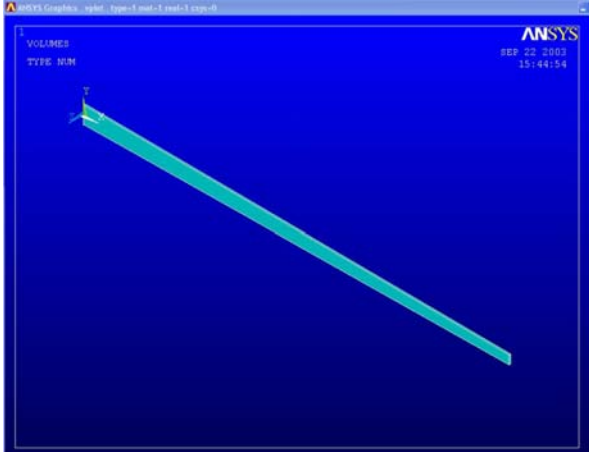
$$y(L_c) = \left(\frac{4F}{EWh^3} \right) L_c^3 \longrightarrow \text{13\% smaller than tapered-width case}$$

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Comparison With Finite Element Simulation

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- Below: ANSYS finite element model with
 - $L = 500 \mu\text{m}$ $W_{\text{base}} = 20 \mu\text{m}$ $E = 170 \text{ GPa}$
 - $h = 2 \mu\text{m}$ $W_{\text{tip}} = 10 \mu\text{m}$



The image shows a screenshot of the ANSYS software interface. It displays a 3D model of a cantilever beam, colored in a light blue/cyan hue, against a dark blue background. The beam is fixed at one end and extends diagonally downwards to the right. The ANSYS logo and some system information (SEP 22 2003 15:44:54) are visible in the top right corner of the window.

- Result: (from static analysis)
 - $k = 0.471 \mu\text{N/m}$
- This matches the result from energy minimization to 3 significant figures

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Need a Better Approximation?

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- Add more terms to the polynomial
- Add other strain energy terms:
 - Shear: more significant as the beam gets shorter
 - Axial: more significant as deflections become larger
- Both of the above remedies make the math more complex, so encourage the use of math software, such as Mathematica, Matlab, or Maple
- Finite element analysis is really just energy minimization
- If this is the case, then why ever use energy minimization analytically (i.e., by hand)?
 - Analytical expressions, even approximate ones, give insight into parameter dependencies that FEA cannot
 - Can compare the importance of different terms
 - Should use in tandem with FEA for design

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